



Serial No.: 10/044,493

Corres. and Mail
BOX AF

AF/2800
6/BNE
P. Whelan
1-29-03

PATENT- AF
RESPONSE UNDER 37 C.F.R. 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2826

CERTIFICATE OF MAILING (37 C.F.R. 1.8a)

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Box AF, Commissioner for Patents, U.S. Patent and Trademark Office, Washington, D.C. 20231.

1/16/2003 Johnette Jernigan
Date Name of person mailing paper


Signature

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Bin Yu, et al.

Serial No.: 10/044,493

Art Unit: 2826

Filed: January 11, 2002

Confirmation No.: 9266

Title: SEMICONDUCTOR DEVICE WITH SILICIDE
SOURCE/DRAIN AND HIGH-K DIELECTRIC

Examiner: Kevin V. Quinto

Docket No.: G0615

RESPONSE UNDER 37 C.F.R. 1.116
TO OFFICE ACTION DATED DECEMBER 4, 2002

Box AF
Commissioner for Patents
U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

This reply is filed in response to the Office action dated December 4, 2002. It is believed that the reply raises no new issues, does not require an additional search and/or

RECEIVED
JAN 28 2003
TECHNICAL CENTER 2800

BEST AVAILABLE COPY

AGENT & TRA

C.F.R. 1.116
DECEMBER 4, 2002

Applicant: Bin Yu, et al

Serial No.: 10/044,493

Art Unit: 2826

Confirmation No.: 9266

Filed: January 11, 2002

Title: SEMICONDUCTOR DEVICE WITH SILICIDE
SOURCE/DRAIN AND HIGH-K DIELECTRIC

Examiner: Kevin V. Quinto

Docket No.: G0615

RECEIVED
JAN 28 2003
TECHNICAL CENTER 2800

A marked version of the amended claim appears below (deletions bracketed and struck through and additions underlined):

20. (amended) A [The] semiconductor device [according to claim 1,]
comprising:

a source and a drain, said source and drain consisting essentially of silicide;
a semiconductor body disposed between the source and the drain, wherein a
source/body junction is defined by silicide material of the source and semiconductor
material of the body and a drain/body junction is defined by silicide material of the drain
and semiconductor material of the body;

a gate electrode disposed over the body and defining a channel interposed
between the source and the drain; and

a gate dielectric made from a high-K material and separating the gate electrode
and the body.
